

Form PTO-1449 (modified) List of Patents and Publications For Applicant's Information Disclosure Statement (Use several sheets if necessary)	ATTY. DKT. NO. 5589-05001 APPLICANT: Xu et al. FILING DATE: October 31, 2003	SERIAL NO. 10/699,352 GROUP: 2658 2829
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U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO
J. m. H	A1	98/57358	1998-12-17	WO			

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

J. m. H	A2	Cosway et al., "Manufacturing Implementation of Corona Oxide Silicon (COS) Systems for Diffusion Furnace Contamination Monitoring," 1997 IEEE/SEMI Advanced Semiconductor Manufacturing Conference, pp. 98-102.
	A3	Miller, "A New Approach for Measuring Oxide Thickness," Semiconductor International, July 1995, pp. 147-148.
	A4	<u>Numerical Recipes in C, The Art of Scientific Computing, 2nd Ed.</u> , © Cambridge University Press 1988, 1992, p. 683.
	A5	Weinberg, "Tunneling of Electrons from Si into Thermally Grown SiO ₂ ," Solid-State Electronics, 1977, Vol. 20, pp. 11-18.
	A6	Verkuil, "Rapid Contactless Method for Measuring Fixed Oxide Charge Associated with Silicon Processing," IBM Technical Disclosure Bulletin, Vol. 24, No. 6, 1981, pp. 3048-3053.
	A7	"Contactless Photovoltage vs. Bias Method for Determining Flat-Band Voltage," IBM Technical Disclosure Bulletin, Vol. 32, Vol. 9A, 1990, pp. 14-17.
	A8	"Contactless Electrical Equivalent Oxide Thickness Measurement," IBM Technical Disclosure Bulletin, Vol. 29, No. 10, 1987, pp. 4622-4623.

EXAMINER:

DATE CONSIDERED:

3/7/05


EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the patent owner.

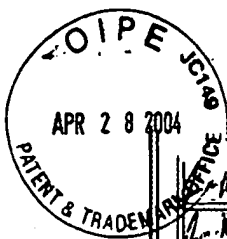


ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	METHODS AND SYSTEMS FOR DETERMINING AN ELECTRICAL PROPERTY OF AN INSULATING FILM							
Application Number: 10/699352								
Confirmation Number: 2525								
First Named Applicant: Zhiwei Xu								
Attorney Docket Number: 5589-05001								
Search string:		(5485091 or 6097196 or 6202029 or 4599558 or 5594247 or 5644223 or 4812756 or 5650731 or 5767693 or 5661408 or 5742658 or 5852232 or 5866806 or 5948972 or 5955661 or 6011404 or 6191605 or 6267005 or 5773989 or 6569691 or 3495269 or 3496352 or 4734721 or 5834941 or 6060709 or 6072320 or 6091257 or 6104206 or 6121783 or 6201999 or 6224638 or 20020090746).pn.						
US Patent Documents								
Note: Applicant is not required to submit a paper copy of cited US Patent Documents								
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass	
<input checked="" type="checkbox"/>	1	5485091	1996-01-16	Verkuil				
<input type="checkbox"/>	2	6097196	2000-08-01	Verkuil et al.				
<input type="checkbox"/>	3	6202029	2001-03-13	Verkuil et al.				
<input type="checkbox"/>	4	4599558	1986-07-08	Castellano et al.				
<input type="checkbox"/>	5	5594247	1997-01-14	Verkuil et al.				
<input type="checkbox"/>	6	5644223	1997-07-01	Verkuil				
<input type="checkbox"/>	7	4812756	1989-03-14	Curtis et al.				
<input type="checkbox"/>	8	5650731	1997-07-22	Fung				
<input type="checkbox"/>	9	5767693	1998-06-16	Verkuil				
<input type="checkbox"/>	10	5661408	1997-08-26	Kamieniecki et al.				
<input type="checkbox"/>	11	5742658	1998-04-21	Tiffin et al.				
<input type="checkbox"/>	12	5852232	1998-12-22	Samsavar et al.				
<input checked="" type="checkbox"/>	13	5866806	1999-02-02	Samsavar et al.				



<input checked="" type="checkbox"/>	14	5948972	1999-09-07	Samsavar et al.
<input checked="" type="checkbox"/>	15	5955661	1999-09-21	Samsavar et al.
<input checked="" type="checkbox"/>	16	6011404	2000-01-04	Ma et al.
<input checked="" type="checkbox"/>	17	6191605	2001-02-20	Miller et al.
<input checked="" type="checkbox"/>	18	6267005	2001-07-31	Samsavar et al.
<input checked="" type="checkbox"/>	19	5773989	1998-06-30	Edelman et al.
<input checked="" type="checkbox"/>	20	6569691	2003-05-27	Jastrzebski et al.
<input checked="" type="checkbox"/>	21	3495269	1970-02-10	Mutschler et al.
<input checked="" type="checkbox"/>	22	3496352	1970-02-17	Jugle
<input checked="" type="checkbox"/>	23	4734721	1988-03-29	Boyer et al.
<input checked="" type="checkbox"/>	24	5834941	1998-11-10	Verkuil
<input checked="" type="checkbox"/>	25	6060709	2000-05-09	Verkuil et al.
<input checked="" type="checkbox"/>	26	6072320	2000-06-06	Verkuil
<input checked="" type="checkbox"/>	27	6091257	2000-07-18	Verkuil et al.
<input checked="" type="checkbox"/>	28	6104206	2000-08-15	Verkuil
<input checked="" type="checkbox"/>	29	6121783	2000-09-19	Horner et al.
<input checked="" type="checkbox"/>	30	6201999	2001-03-13	Jevtic
<input checked="" type="checkbox"/>	31	6224638	2001-05-01	Jevtic et al.

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
<input checked="" type="checkbox"/>	1	20020090746	2002-07-11	Xu et al.			

Signature

Examiner Name	Date
<i>John H. [Signature]</i>	3/7/05